

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Jiangang Sun

Serial No.:

Art Unit:

Filed: Concurrently

Examiner:

Title: DEVICE AND NONDESTRUCTIVE METHOD TO DETERMINE SUBSURFACE
MICRO-STRUCTURE IN DENSE MATERIALS

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.56 AND 1.97

Commissioner of Patents and Trademarks
Washington, D.C. 20231

Sir:

The citations listed on the accompanying form PTO 1449 are submitted in compliance with the duty of disclosure as defined in 37 CFR 1.56 and 1.97.

U.S. Patent No. 6,285,449 awarded to Ellingson et. al., September 2, 2001, describes the scattering detection method known as cross-polarization confocal microscopy.

U.S. Patent No. 5,689,332 awarded to Ellingson et. al., November 18, 1997, describes an automated real time detection device for identifying defects during the machining of ceramics.

H.R. Hee et. al." OPTICAL COHERENCE TOMOGRAPHY FOR OPHTHALMIC IMAGING", *IEEE Engineering in Medicine and Biology*, 1995, at 67, describes the optical coherence tomography method of detection.

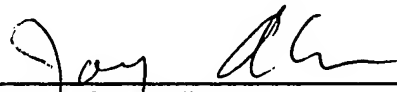
Sun et. al. "APPLICATION OF OPTICAL SCATTERING METHODS TO DETECT DAMAGE IN CERAMICS, in *MACHINING OF CERAMICS AND COMPOSITES*, Part IV; Chapter 19, edited by Jahanmir et. al., 1999, at 669, describes cross-polarization confocal

microscopy.

Zhang et. al. "SUBSURFACE DAMAGE MEASUREMENT IN SILICON WAFERS BY LASER SCATTERING", in *TRANSACTIONS OF NAMRI/SME*, Vol XXX, 2002, at 535, also describes cross-polarization confocal microscopy.

This disclosure submission is not to be construed as a representation that a search has been made, that additional matter material to the examination of this application does not exist, or that any one or more of these citations constitutes prior art under 35 U.S.C 102.

Respectfully submitted,



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Date Dec 4, 2003

Attachments
As Stated

<p style="text-align: center;">INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)</p>	<p>Docket Number (Optional) S-101,670</p>	<p>Application Number</p>
<p>Applicant(s) Jiangang Sun</p>		
<p>Filing Date</p>	<p>Group Art Unit</p>	

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		6,285,449	9/2/01	Ellingson, et al.			
		5,689,332	11/18/97	Ellingson, et al.			

FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		H. R. Hee, et al. "Optical Coherence Tomography for Ophthalmic Imaging", IEEE Engineering in Medicine and Biology, 95 Sun, et al., "Application of Optical Scattering Methods to Detect Damage in Ceramics", in Machining of Ceramics and Composites, Part IV; Chapter 19, edited by Jahanmir et al., in 1999, It 669.
		Zhang et al., "SUBSURFACE DAMAGE MEASUREMENT IN SILICON WAFERS BY LASER SCATTERING", in Transactions of NAMS/SME, Vol. XXX, 2002, at 535.

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.